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U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

10A15

APPL NUM 10068005	FILING DATE 02/08/2002	CLASS 46 118	SUBCLASS 118	GAU 1763	EXAMINER <i>[Signature]</i>
**APPLICANTS: Jung Hyo-Sang; <i>Redacted</i>					
**CONTINUING DATA VERIFIED:					
** FOREIGN APPLICATIONS VERIFIED: REPUBLIC OF KOREA 2001-8175 02/19/2001					
PG-PUB <input type="checkbox"/> DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>			
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no Verified and Acknowledged Examiners's initials				ATTORNEY DOCKET NO 262/011	
TITLE : Vacuum apparatus of ion implantation system and evacuation method <small>U.S. DEPT. OF COMM./PAT & TM-PTO-436L (Rev. 12-94)</small>					

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		Primary Examiner	DRAWING	
Amount Due	Date Paid		Sheets Drwg.	Figs. Drwg.
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	Application Examiner	
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